REMARKS

The above amendment to the claims has been made to correct the multiple dependency of the claims and to put the application in better condition for examination.

Attached hereto is a marked-up version of the changes made to the claims by the current amendment. The attached page is captioned "Version with Markings to Show Changes Made."

In the event that any fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, WESTERMAN, HATTORI, McLELAND & NAUGHTON, LLP

Attorney for Applicants Reg. No. 32,878

Atty. Docket No. 011019

1725 K Street, N.W., Suite 1000

Washington, DC 20006 Tel: (202) 659-2930

Fax: (202) 887-0357

SGA/ll

VERSION WITH MARKINGS TO SHOW CHANGES MADE

IN THE CLAIMS

Claims 3, 6-10 have been amended as follows:

- 3. (Amended) The position indicator of Claim[1]2, wherein the elastic film [of Claim 2] forms concavity to provide the maximum momentum to the air.
- 6. (Amended) The position indicator of Claim[1]4, wherein the cover [of Claim 4] comprises a cover comprising another holes on the outside to prevent the pressure sensor from wind.
- 7. (Amended) The position indicator of Claim [1]2, wherein the elastic film [of Claim 2] is comprised of a piezoelectric film having a piezoelectric effect.
- 8. (Amended) The position indicator of Claim [1]7, wherein the piezoelectric film [of Claim 7] is glued to another film, comprised of a material with good elasticity and rigidity, which fills a role of pushing air.
- 9. (Amended) The position indicator of Claim [1]2, wherein the reaction of the air due to the movement of the position indicator is calculated by measuring a change in an output of a photo sensor which receives a reflected light of a light emitted towards the elastic film [of Claim 2].

10. (Amended) The position indicator of Claim[1] 2, wherein the elastic film [of Claim 2] is comprised of a silicon, a piezo resistive element is set near the elastic film and a deflection occurred by the elastic film pushing the air is measured by a change in a resistance value of the piezo resistive element.